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PRAD		FINFORMATION DISCL		Docket No. 16627-US-DIV				
	(٤	Jnder 37 CFR 1.97(b) or 1.9	7(c))	10027 00 217				
In Re A	pplication Of: Re	abah BOUKHERROUB, et al.						
Serial No.		Filing Date	Examiner	Group Art Unit				
10/	830,035	23 April 2004						
Title:	PASSIVATION	OF POROUS SEMICONDUCT	ORS					
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		Assistant Com	ddress to: missioner for Patents iton, D.C. 20231					
		37 CI	FR 1.97 (b)					
1. 🗷	The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application; within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; or before the mailing date of a first Office Action on the merits, whichever event occurs last.							
		37 CI	FR 1.97 (c)	·				
2.	of a national a international a	n Disclosure Statement submitt pplication, or the date of entry of pplication; or after the mailing ut before the mailing date of eith	of the national stage as set to date of a first Office Action	forth in 37 CFR 1.491 in an				
	1.	a Final Action under 37 CFR	1.113, or					
	2.	a Notice of Allowance under	37 CFR 1.311,					
	whiche	ever occurs first.						
	Also submitted herewith is:							
	a certific	ation as specified in 37 CFR 1.	97(e);					
		OR		•				
		set forth in 37 CFR 1.17(p) fo 7 CFR 1.97(c).	or submission of an Informa	ation Disclosure Statement				
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TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT

Docket No.

DEMARY	(U	nder 37 CFR 1.97(b) or 1.97	(c))	16627-US-DIV			
		oah BOUKHERROUB, et al.					
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	Serial No. Filing Date		Examiner	Group Art Unit			
10	/830,035	23 April 2004					
Title	PASSIVATION C	F POROUS SEMICONDUCTO	PRS				
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		cument and authorization to charge ing facsimile transmitted to the United		ent and fee being deposited ith the U.S. Postal Service as			
		demark Office (Fax. No.	first class mail under 37 C.F.R. 1.8 and addressed to the Assistant Commissioner for Patents, Washington, D.C.				
	(Date)		20231.	or Faterits, Washington, D.C.			
	(Date)	·					
		Signature	Signature of Person	Mailing Correspondence			
	Typed pr Printed	Name of Person Signing Certificate	Typed or Printed Name of P	Person Mailing Correspondence			
	*This certificate m deposit account.	ay only be used if paying by		- -			
	1251	Zohl	Dated: 29 June 2	004			
D:		ignature II					
Richard J. Mitchell							
34,519							
Marks & Clerk Canada							
P.O. Box 957 Station B							
	awa, ON, K1P 5	5S7					
	Phone: (613) 236-9561						

PTO/SB/08b (08-03) Approved for use through 06/30/2006. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Substitute for form 1449B/PTO				Complete if Known			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Application Number	10/830,035		
				Filing Date	23 April 2004		
				First Named Inventor	Rabah BOUKHERROUB		
				Art Unit			
				Examiner Name			
Sheet	1	of	1	Attorney Docket Number	16627-US-DIV		

Signature

work Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

		NON PATENT LITERATURE DOCUMENTS		
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
		SIEVAL, A. B., et al., "Highly stable Si-C linked functionalized monolayers on the silicon (100) surface", 1998, Vol. 14, No. 7, pages 1759-1768.		
		BATEMAN, James E., et al., "Alkylation of porous silicon by direct reaction with alkenes and alkynes", Angew. Chem. Int. Ed., 1998, 37, Vol. 19, pages 2683-2685.		
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^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not

Considered

considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.